



Powering the Integrated Microsystem

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| Program | Goal |
|---------------------------------------------|-------------------------------------------------------------------------------------------------------------------------------------------------------------------|
| 3-D MERFS | Enable dramatic reduction in size (30x) and cost (100x) for MMW systems by demonstrating a new air-core-coax "printed circuit board" technology for MMW. |
| Analog Spectral Processors | Enable dramatic decreases in radio size and power by simultaneously trading advances in new radio architectures and new MEMS filters. |
| Disruptive Manufacturing Technologies | Exploit opportunities to dramatically decrease manufacturing costs for existing military systems. |
| Micro Electric (Space) Propulsion | Demonstrate thrusters with wide Isp dynamic range, enabling spacecraft to flexibly respond to changing national needs. |
| Micro Isotope Power Sources | Demonstrate high-energy-density isotope batteries. |



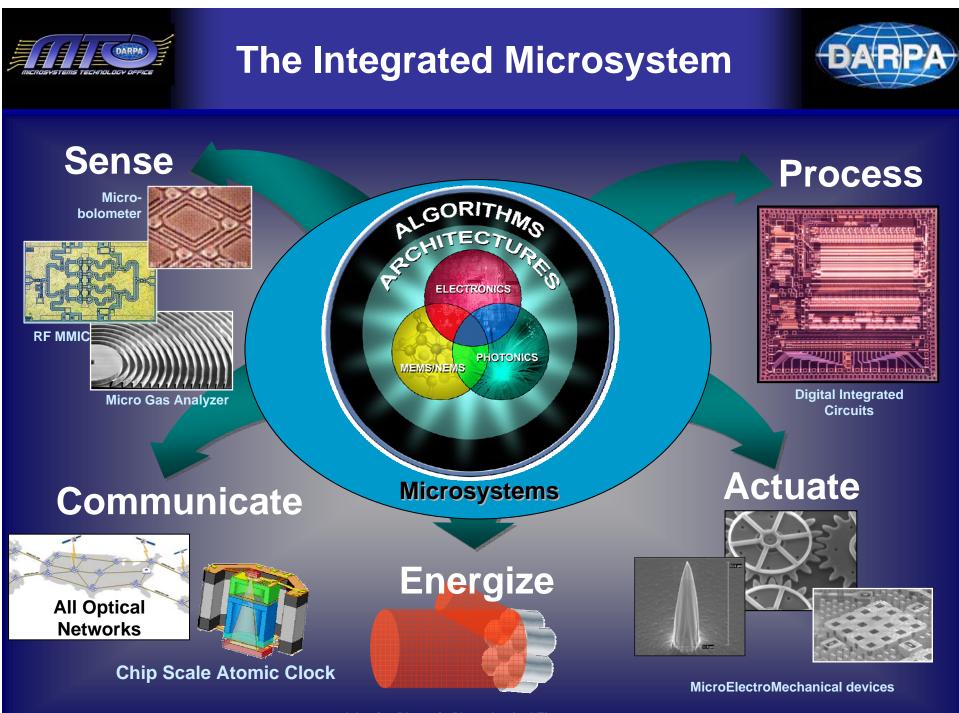




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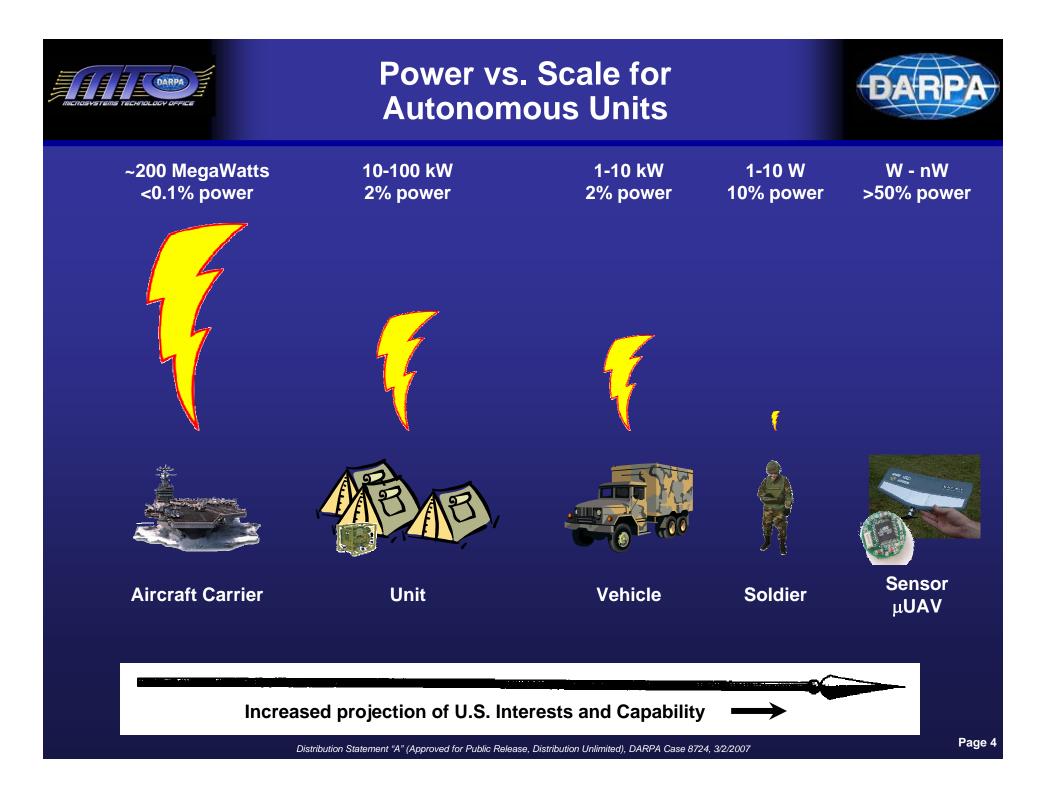


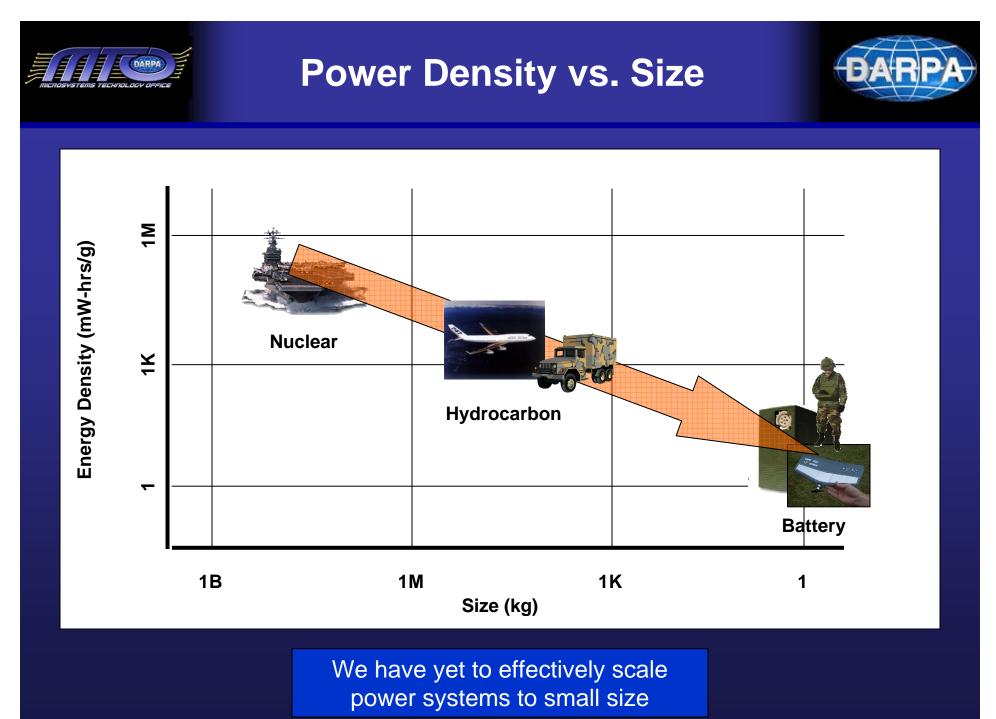
ARPA SPA



Adaptive Photonic Phase-Locked Elements

Distribution Statement "A" (Approved for Public Release, Distribution Unlimited)









Use Less Power





<u>Analog Spectral Processors</u> Dramatic decrease in radio power by off-loading RF signal processing to passive MEMS filter arrays.



Chip Scale Atomic Clock

300X reduction in power consumption (from 10 W to <30 mW) for atomic clocks through system miniaturization.



Energy Starved Electronics Demonstrate 100X improvement in energy per operation over conventional electronics through sub threshold operation.



Micro-Gas Analyzers

10,000x decrease in power required per analysis through system miniaturization.



Super High Efficiency Diode Sources 80% electrical-to-optical efficiency from semoconductor diode laser bars (880nm to 980nm)



Micro Electric (Space) Propulsion Doubling of electrical efficiency for electric propulsion systems through miniaturization.



Scale Macro Power Systems

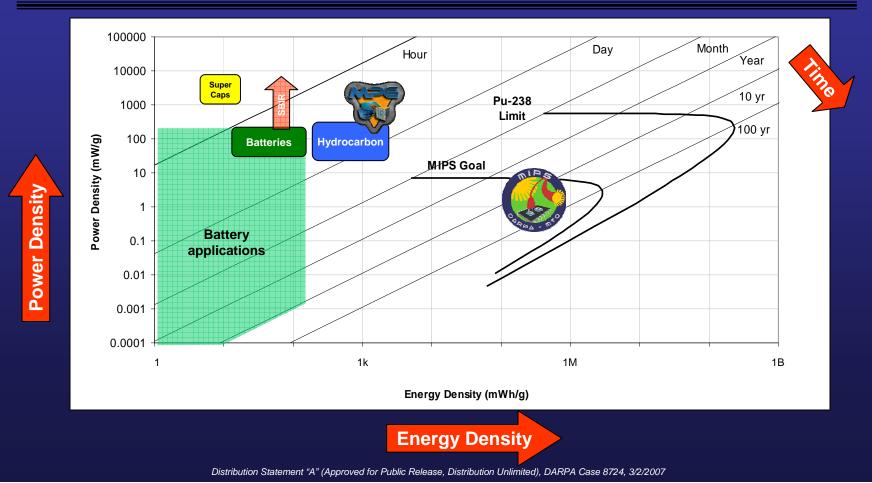




<u>Micro Isotope Power Sources</u> Small power sources based on energy conversion from isotopes.



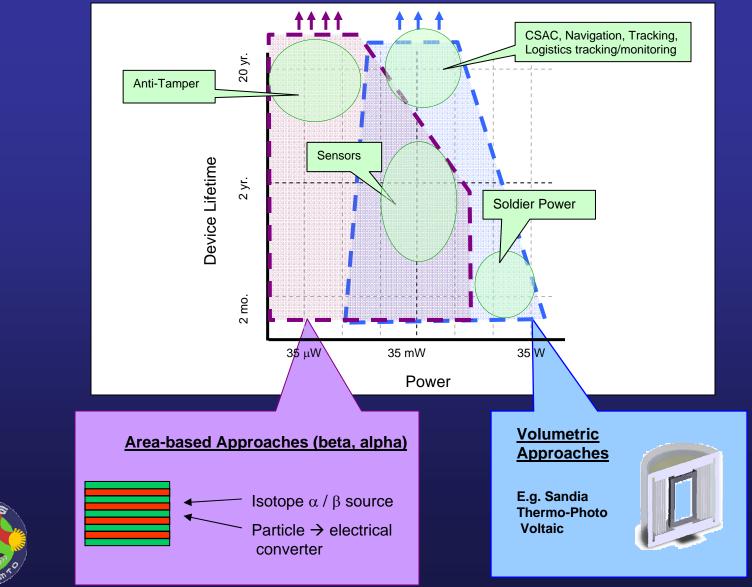
<u>Micro Power Generation</u> Micro-scale power generation from hydrocarbon fuel





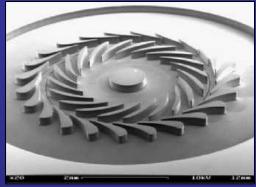
Micro Isotope Power Sources



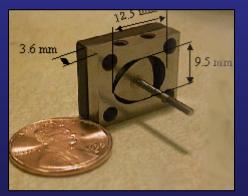


Micro-Hydrocarbon Conversion Challenging





MIT Micro-Turbine



Berkeley Micro-Wankel



USC Swiss-Roll counter-flow heat exchanger



...most have run into significant technical challenges as they move to micro-scale.



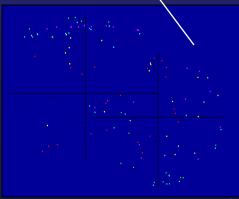


Micro-Hydrocarbon Conversion Challenging



Some challenges

- As you miniaturize, surfacearea-to-volume increases. Drives inefficiencies...
 - Thermal losses (quenching)
 - Friction (bearings)
 - Viscous losses in liquid flow
- Poor mixing on micro-scale
 - Low Reynolds numbers poses limits on use of turbulence
 - Diffusion insufficient
 - Chaotic mixing limited by 2-D nature of micro-fabricated systems.



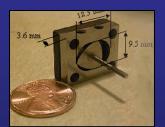
J. Evans, Poincare maps for perturbed quadra-pole mixer



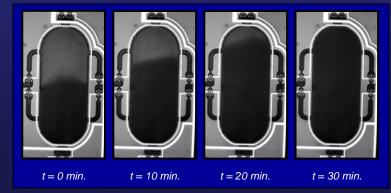
USC Swiss-Roll counter-flow heat exchanger



MIT Micro-Turbine



Berkeley Micro-Wankel

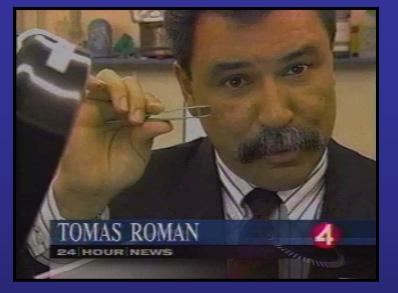


J. Evans, 82 nl, 100 µm x 600 µm x 1500 µm



The Challenge of Microfluidics...



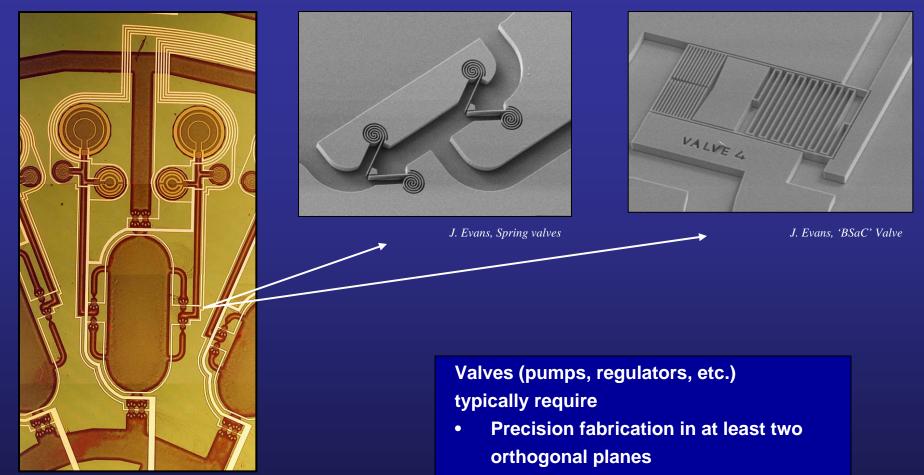






Microfluidics Limited by Geometric & Materials Constraints





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J. Evans, Quadra-Pole mixer

Multiple material properties for structure, seal, etc.

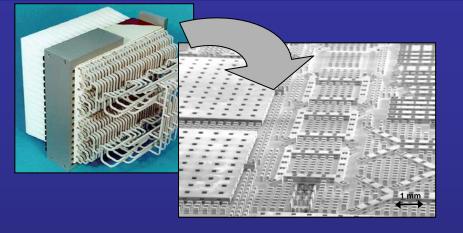


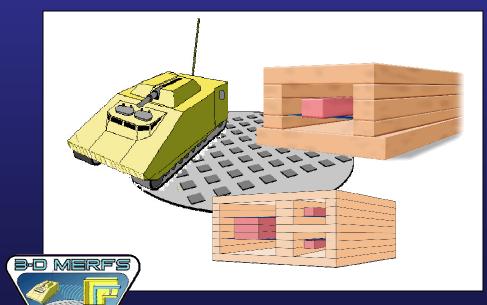
DARP

MTO

3-D MERFS John D. Evans







Goal:

Demonstrate an affordable, high performance 3-D "Printed Circuit Board" technology for RF/MMW based upon air-core Recta-coax.

Technical Challenges

Phase I:

- Precision 3-D fabrication using new material system that utilizes air (sacrificial material), copper, and structural polymer.
- Demonstration of new *sacrificial* high-aspect-ratio photo resist.
- Demonstration of new metal/polymer/copper CMP process.

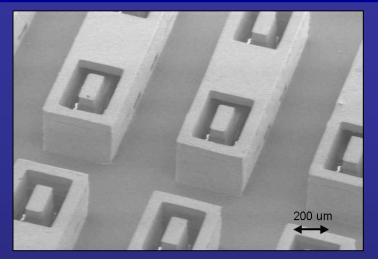
Phase II:

- Double number of lithographic layers $(5 \rightarrow 9)$, thereby enable crossovers and doubling RF performance.
- Balance layer adhesion vs. CMP shear stress.
- Improve fabrication yield.

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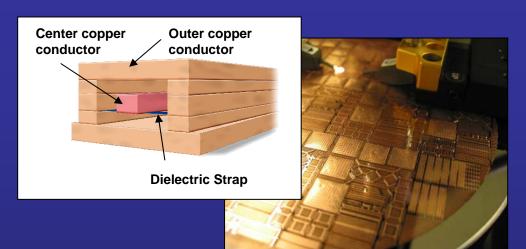
Images of 3-D MERFS Structures (5 lithographic layers, 3 Material)



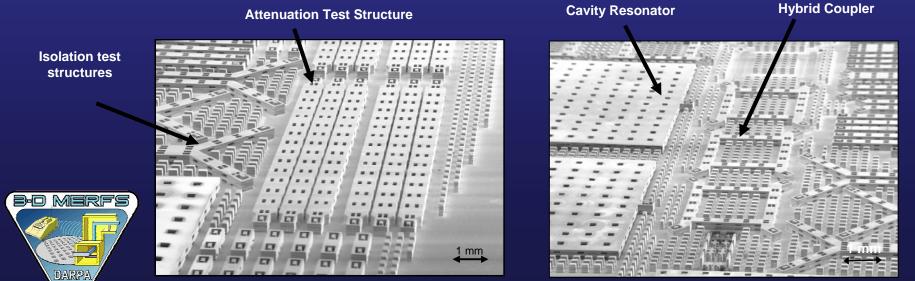


"Launch" De-imbedding Test Structures

MTO.



6-Inch 3-D MERFS Wafer on RF Probe Station

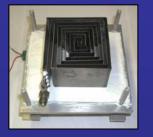


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Maybe its time for a new push...

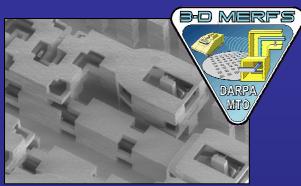




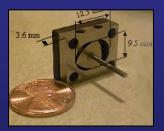
USC Swiss-Roll counter-flow heat exchanger



MIT Micro-Turbine



New Polystrata[™] Fabrication Technology Enables complex 3-D MEMS Geometries



Berkeley Micro-Wankel



CalTech Micro-Solid Oxide Fuel Cell Critical mass of new ideas?

Who's the next Power PM?



Maybe it's you...









Powering the Integrated Microsystem

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